

LCLS Vacuum PV List

LCLS Vacuum Controls Database PV Attributes

Table 1.0 provides the format of the EPICS PV name. Table 1.1 lists the Vacuum Primaries used for LCLS. Table 1.2 lists the most commonly used EPICS PV attributes.

Vacuum Device Name Examples
Table 1.0
EPICS Device
<Device Type>:<Area>:<Position>: <Attribute>

Vacuum Device Types	
Table 1.1	
Device Type	Description
VVPG	Pneumatic (remotely controlled) gate valve
VVMG	Manual gate valve

VPI	Ion pump
O	

VGC	Cold cathode gauge
VGPR	Pirani gauge
VGHF	Hot filament gauge
VGCP	Convectron gauge

Vacuum Attributes		
Table 1.2		
Device Type	Attribute	Description
VVPG or VVMG	POSITION	Valve position. Options: Open, Closed, Moving, Inconsistent

VPI	P	Pressure (Torr)
O		
VPI	V	Pump voltage (Volts)
O		
VPI	I	Pump current (Amps)
O		
VPI	PSTAT	Pressure status relative to process set point 1. Options: OK, Faulted
O	1	
VPI	PSTAT	Pressure status relative to process set point 2. Options: OK, Faulted
O	2	

VGCC, VGPR, VGHF, or VGCP	P	Pressure (Torr)
VGCC, VGPR, VGHF, or VGCP	PSTA	Pressure status relative to process set point. Options: OK, Faulted
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